

### 5.1.2 RHE MICROSYSTEMS

The Process Capability Approval (PCA) of the Hybrid Line RHe Microsystems in Radeberg, Germany, has been certified by ESA in accordance with the requirements of ESCC Basic specification No. 2566000.

The associated PID includes RHe's manufacturing, assembly and test operations which have been approved for the supply of Hermetic Hybrid products for use in ESA space systems as a Category1, Option 1 Manufacturer, in accordance with ECSS-Q-ST-60-05C Rev.1

#### 5.1.2.1 Contact Information

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#### 5.1.2.2 Process Capability Approval

Certificate No.	Certified since:	Type Designation
354		Thick Film Hermetic Hybrid Integrated Circuits and HTCC Hermetic Hybrid Integrated Circuits

### 5.1.2.3 Capability Abstract

RHe's hybrid manufacturing line capabilities are defined within the associated Process Identification Document (PID) L7.103 Issue 07.

This specifiction describes all processes, components/materials and their documentation used by RHe for the production, screening, test and quality control of the following Hybrid types:

- •Thick Film Multilayer Hybrid up to 5 conductive layers
- •Low / Medium Power, Low-Voltage
- Chip and Wire
- •Hermetically sealed Kovar-and Ceramic- Packages.

Processes run on state of the art automated equipment to realize requirements in regard to process capability and volume.



## Details to the general Process Capability Domain:

### Substrate information:

Subtechnique	Domain
Substrate Material:	Al2O3
Max No. of screen printed conductor layers:	5
Untrimmed Printed resistors:	
Min sheet resistance	10Ω/sq
Max sheet resistance	1MΩ/sq
Trimmed Printed resistors:	
Min sheet resistance	10Ω/sq
Max sheet resistance	1MΩ/sq

# Assembly Information:

## o Substrate attach:

Substrate type	Back	Attached to	Attached by	Inter-
	metallization			connection
Thick film alumina	No	Au plated	Non-conductive	AI / Au wire
		Kovar	Ероху	
Thick film alumina	No	Au plated	Non-conductive	Al / Au wire
		W/Cu	Ероху	
Thick film alumina	No	HTCC	Non-conductive	AI / Au wire
			Ероху	

### o Element attach:

Compone nt type	Material	Top metal.	Bottom metal	Attachment	Inter- connection
passive cor	nponents:				
Resistor	Si	Al	Si	Non-conductive Epoxy	Al wire
Capacitor	Multilayer ceramic	N/A	AgPd	Conductive + Non-conductive epoxy	Conductive epoxy
active comp	active components:				
IC	Si	Al	Si	conductive epoxy	Al / Au wire
Transistor	Si	Al	Au	conductive epoxy	Al wire
Transistor	Si	Al	CrNiAg	conductive epoxy	Al wire
Transistor	Si	Al	Ti/Ni/Au	reflow soldering	Al wire
Diode	Si	Al	Au	conductive epoxy	Al wire
Diode	Si	Al	Ti/Ni/Au	reflow soldering	Al wire

## o Encapsulation:

Package type	Material	Sealing by
Metal FP	Kovar	Seam welding



	Au finish	
Metal FP	W/Cu base	Seam welding
	Kovar frame Au finish	
Metal Plug In	Kovar	Seam welding
		3
	Au finish	
Ceramic Quad	HTCC base	Seam welding
Flat Package	Kovar frame	
(CQFJ)	Au finish	

## Screening / LAT information:

Screening as well as Lot acceptance testing is performed according to the PID in conformance to the generic procurement specification ECSS-Q-ST-60-05C Rev.1.